Abstract of the Disclosure

A method for monitoring at least one server in a semiconductor factory automation (FA) system, includes the steps of: a) providing server state information from at least one server to a real-time database, wherein the server state information includes an availability of a central processing unit, an availability of a disk and a state of a program process related to the server; b) storing the processor state information in the real-time database; c) retrieving the server state information to monitor the server; and d) displaying the server state information retrieved. Therefore, the method monitors at least one server in a real time so that an operator can easily locate a failure of at least one server.

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